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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Michael Steigerwald, et al.

Confirmation No.: 7784

Patent No.: 6,949,744 *B2*

Art Unit: 2881

Issued: September 27, 2005

Examiner: Bernard Souw

For: ELECTRON MICROSCOPY SYSTEM,  
ELECTRON MICROSCOPY METHOD  
AND FOCUSING SYSTEM FOR  
CHARGED PARTICLES

Attorney Docket No: 861840-999026

REQUEST FOR CERTIFICATE OF CORRECTIONCommissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450Certificate  
OCT 27 2005  
of Correction

Sir:

Upon review of the subject patent, Applicants attorney discovered typographical errors in the patent for which the Patent Office is at fault. Applicants attorney hereby request corrections of the issued patent. A Form PTO 1050 Certificate of Correction is enclosed in duplicate.

No fees are believed to be due. However, the Commissioner is authorized to charge any required fees or credit any overpayments to Jones Day Deposit Account No. 50-1432. A copy of this page is enclosed for such purpose.

Respectfully submitted,

Date: October 21, 2005*James W. Peterson*  
James W. Peterson  
JONES DAY26,057  
(Reg. No.)2882 Sand Hill Road, Suite 240  
Menlo Park, CA 94025  
(650) 739-3939

OCT 28 2005

# UNITED STATES PATENT AND TRADEMARK OFFICE

## CERTIFICATE OF CORRECTION

PATENT NO. : 6,949,744 B2  
 ISSUED : September 27, 2005  
 INVENTOR(S) : Michael Steigerwald, et al.

It is certified that errors appear in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 12, line 41 of the specification:

"17b<sub>1</sub>, 17d<sub>2</sub> and 17d<sub>3</sub>, ..." should read --17d<sub>1</sub>, 17d<sub>2</sub> and 17d<sub>3</sub>, ...--;

Column 12, line 53 of the specification:

"..., the electron microscopy system id does not ..." should read --..., the electron microscopy system 1d does not ...--;

Column 14, line 9 of the specification;

"An electron microscopy system if schematically shown in ..." should read --An electron microscopy system 1f schematically shown in ...--;

Column 16, line 23 of the specification;

"... time to is depicted." should read --time t<sub>0</sub> is depicted.--;

Column 16, line 27 of the specification;

"At the time to the electrical field..." should read --At the time t<sub>0</sub> the electrical field ...--;

Column 24, line 1 of claim 42:

"... detecting a time structure of electron intensifies of ..." should read --... detecting a time structure of electron intensities of ...--; and

Column 24, line 11 of claim 42:

"...tion of the secondary caused by the deflecting electro-..." should read --tion of the secondary electrons caused by the deflecting electro- ...".

MAILING ADDRESS OF SENDER:  
 JONES DAY  
 2882 Sand Hill Road, Suite 240  
 Menlo Park, CA 94025  
 (650) 739-3939

FORM PTO 1050

PATENT NO.

6,949,744

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